

<b>Notice of References Cited</b>	Application/Control No. 10/725,381	Applicant(s)/Patent Under Reexamination LEE, HAN-CHOON	
	Examiner Heather A. Doty	Art Unit 2813	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	B	US-			
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	D	US-			
	E	US-			
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	J	US-			
	K	US-			
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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Jai-Sik Min, Hyung-Sang Park, Sang-Won Kang, Metal-orgnaic atomic-layer deposition of titanium-silicon-nitride films, Applied Physics Letters Volumne 75, Number 11, 13 September 1999.
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.